

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s) : **Hong Hocheng, Chin Chung Nien**  
Date : **Feb. 16, 2004**  
Serial No. :  
Group Art Unit:  
Filed :  
For : **NANO-IMPRINT SYSTEM WITH MOLD DEFORMATION  
DETECTOR AND METHOD OF MONITORING THE SAME**

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Honorable Commissioner of Patents  
and Trademarks  
Washington, D.C. 20231

INFORMATION DISCLOSURE STATEMENT

Sir:

Attached is a completed Form PTO-1449. List of prior art and Comments on any non-English-language references (if any) pursuant to Rule are submitted herewith.

Respectfully submitted

Applicants(s): Willy Chay \_\_\_\_\_  
Chin Chung Nien \_\_\_\_\_  
\_\_\_\_\_

FORM PTO-1449 (Substitute)			ATTY. DOCKET NO. <u>04130-UPS</u>	SERIAL NO.			
<b>LIST OF PRIOR ART CITED BY APPLICANT</b> <i>(Use several sheets if necessary)</i>			APPLICANT <b>Hong Hocheng, Chin Chung Nien</b>				
			FILING DATE	GROUP			
<b>U.S. PATENT DOCUMENTS</b>							
*EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APROPRIATE
	AA	5,772,905	Jun. 30, 1998	Chou	216	44	Nov. 15, 1995
	AB	6,309,580	Oct. 30, 2001	Chou	264	338	Jun. 30, 1998
	AC						
	AD						
	AE						
<b>FOREIGN PATENT DOCUMENTS</b>							
	AF						
	AG						
	AH						
<b>OTHER PRIOR ART (Including Author, Title, Date, Pertinent Pages, Etc.)</b>							
	AI						
	AJ						
	AK						
	AL						
	AM						
	AN						
	AO						
EXAMINER			DATE CONSIDERED				

\*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.